

FORM PTO-1449

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H16-26635
1100.1116101

Serial No.:

09/749,171

Applicant: Cabuz et al.

LIST OF PATENTS AND PUBLICATIONS FOR
APPLICANT'S INFORMATION
DISCLOSURE STATEMENT

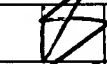

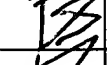
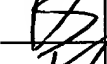

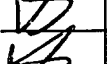
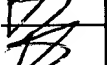

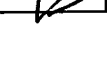
Filing Date:

December 27, 2000

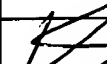
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2812

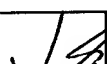


U.S. PATENT DOCUMENTS

Examiner Initial	Document No.	Date	Name	Class	Sub Class	Filing Date If Appropriate
	4,855, 544	8/8/1999	Glenn			
	5,013,681	5/1991	Godbey at al.			
	5,343,064	8/1994	Spangler et al.			
	5,542,558	8/1996	Benz et al.			
	5,866,469	2/1999	Hays			
	5,994,204	11/1999	Young et al.			
	6,277,666	8/2001	Hays et al.			
	2001/002907	10/2001	Kuwahara et al.			
	6,372,609	4/2002	Aga et al.			

FOREIGN PATENT DOCUMENTS

Examiner Initial	Document No.	Date	Country	Translation Yes No
	WO 0078667 A	12/28/2000	PCT	

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

	Mochida, Y., et al., "A micromachined vibrating rate gyroscope with independent beams for the drive and detection modes", Sensors and Actuators A, 80 (2000) pages 170-178.
	Puers, R., et al., "Design and processing experiments of a new miniaturized capacitive triaxial accelerometer", Sensors and Actuators A 68 (1998) pages 324-328.
	Xiao, Zhixiong, et al., "Silicon micro-accelerometer with mg resolution, high linearity and large frequency bandwidth fabricated with two mask bulk process", Sensores and Actuators 77 (1999), pages 113-119.

EXAMINER:

DATE CONSIDERED:

5/15/03

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.